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(54) Title: SELECTIVE CONTROL OF MULTI-STATION PROCESSING CHAMBER COMPONENTS

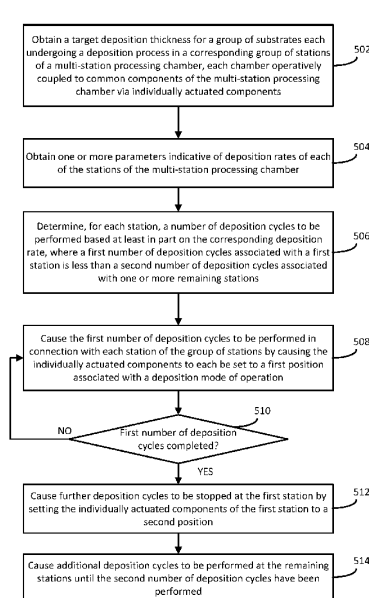


FIG. 5

(57) Abstract: Various embodiments herein relate to apparatuses, systems, and methods for selective control of multi-station processing chamber components. In some embodiments, a method comprises: determining for a station of a plurality of stations, a number of deposition cycles to be performed; causing a first number of deposition cycles to be performed for each of the plurality of stations by causing a first plurality of control components associated with a first station and a second plurality of control components associated with a second station to be set to a first position; and responsive to determining that the first number of deposition cycles has been completed: causing at least one component of the first plurality of control components to be changed to a second position; and causing additional deposition cycles to be performed for the second station by causing the second plurality of control components to remain in the first position.

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